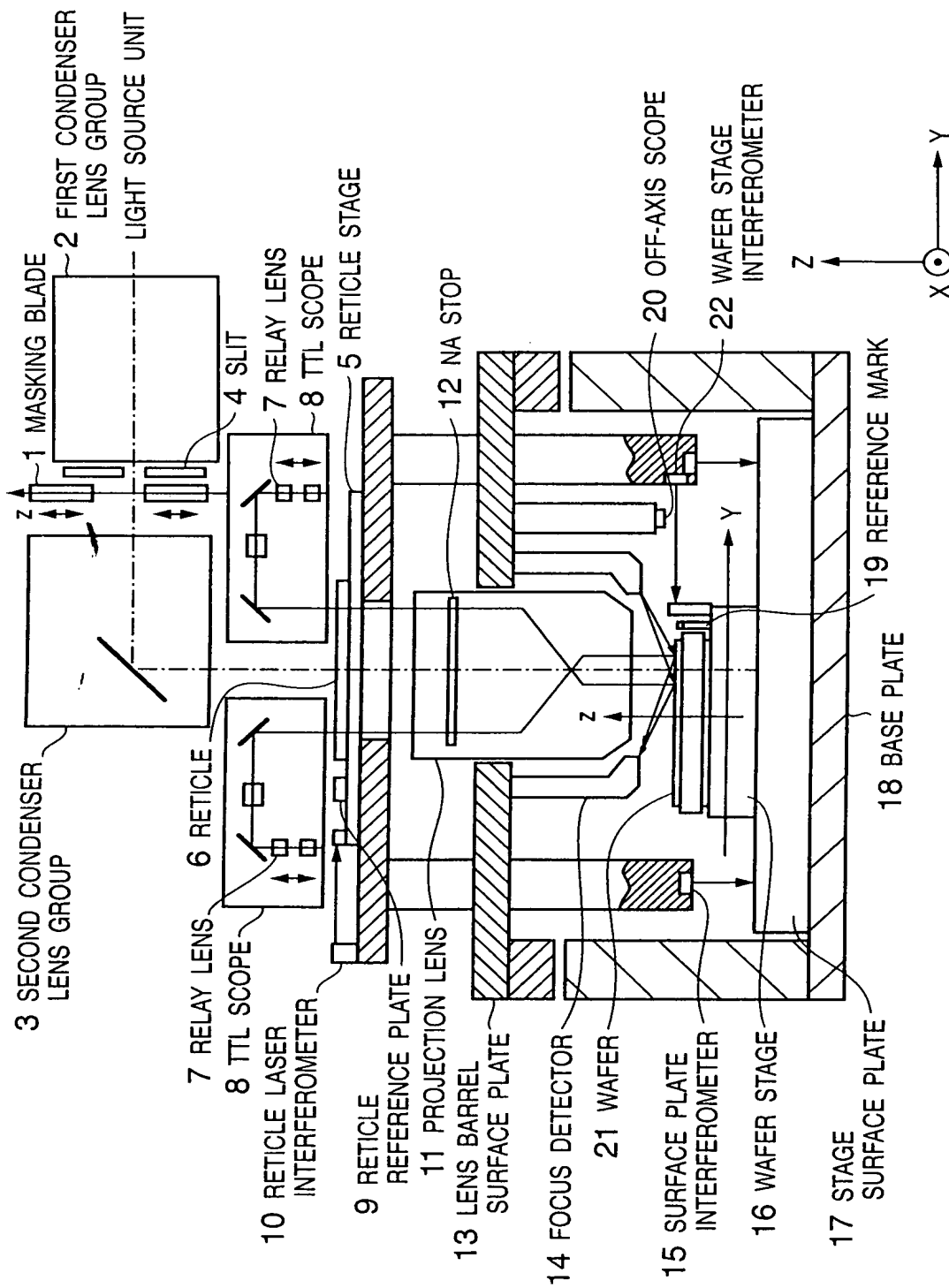


FIG. 1



**FIG. 2**

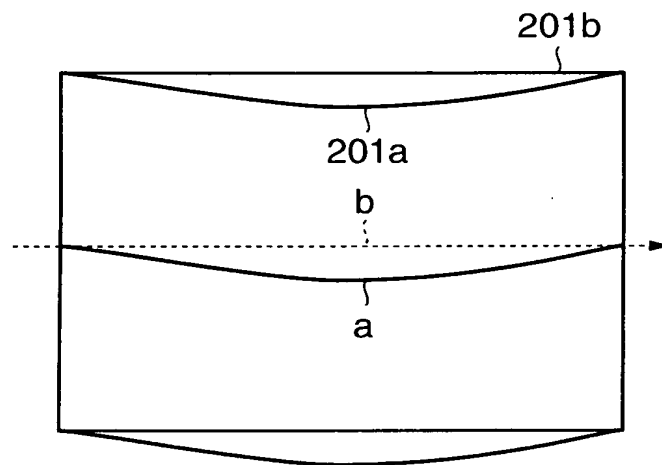
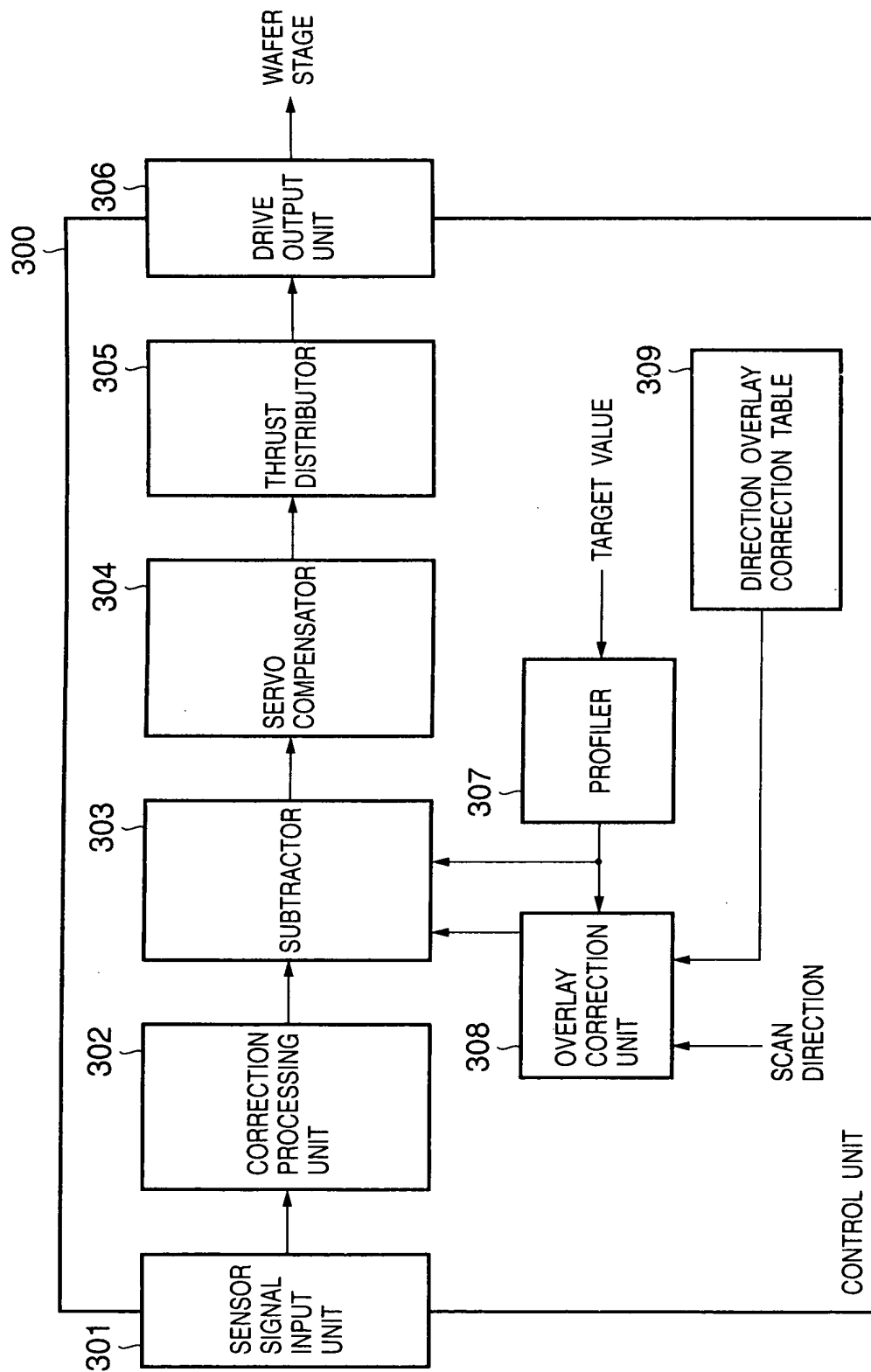
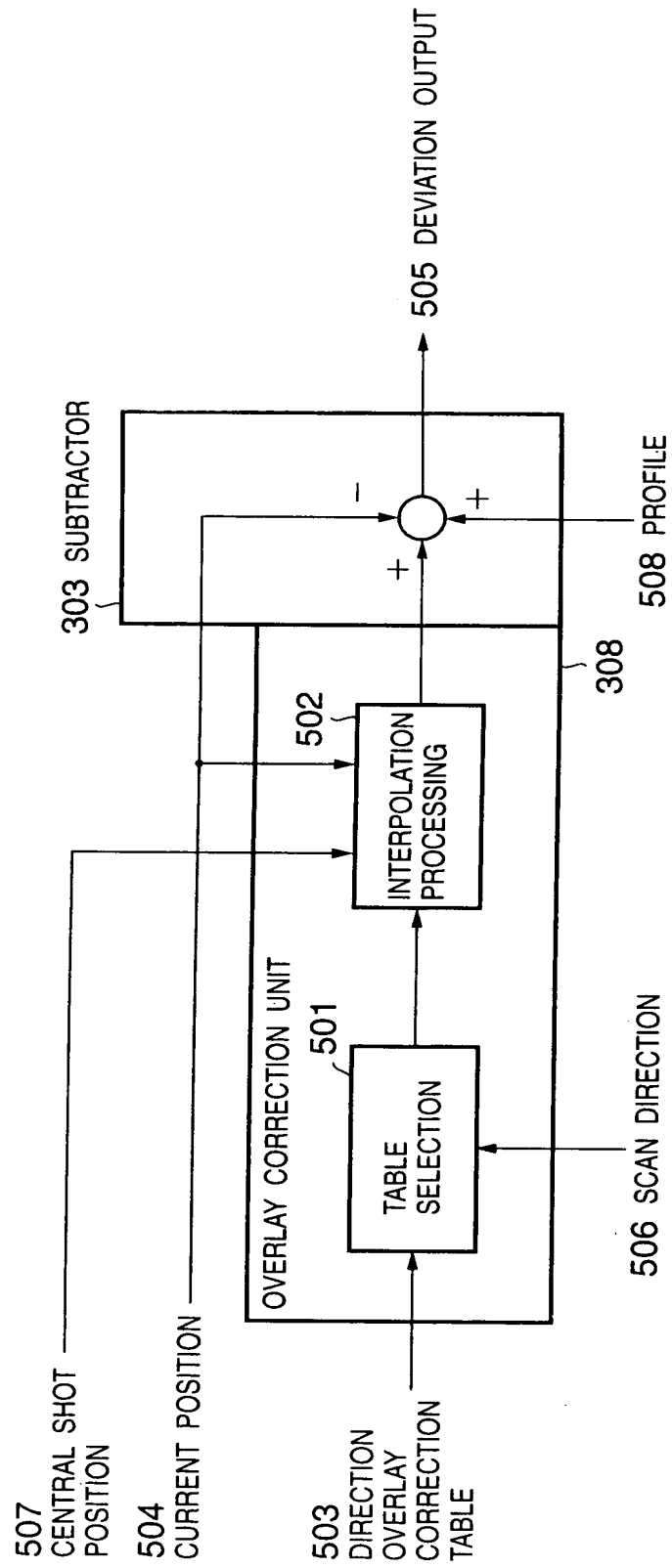


FIG. 3



[illegible]

FIG. 5



# FIG. 6

ORIGIN INTERVAL			-16.000 4.000	[mm] [mm]		
CORRECTION DATA (FORWARD)				[nm/ppb]		
X	Y	Z	Qx	Qy	Qz	
5	1	10	0	-10	20	
4	1	8	10	-10	10	
2	0	10	20	20	10	
1	-1	12	20	40	10	
-1	-4	13	20	30	0	
-4	-2	10	40	40	-10	
-3	-4	7	10	50	-30	
-6	-5	4	0	80	-30	
-12	-9	0	-20	60	-40	
(REVERSE)						
X	Y	Z	Qx	Qy	Qz	
4	0	9	10	-10	20	
2	0	6	0	0	10	
0	-1	11	10	10	10	
0	-1	11	20	30	20	
-3	-4	10	40	10	0	
-5	-3	9	20	40	-10	
-5	-4	6	20	60	-30	
-7	-5	4	10	100	-30	
-14	-9	-1	0	80	-30	

10050581.011802

FIG. 7

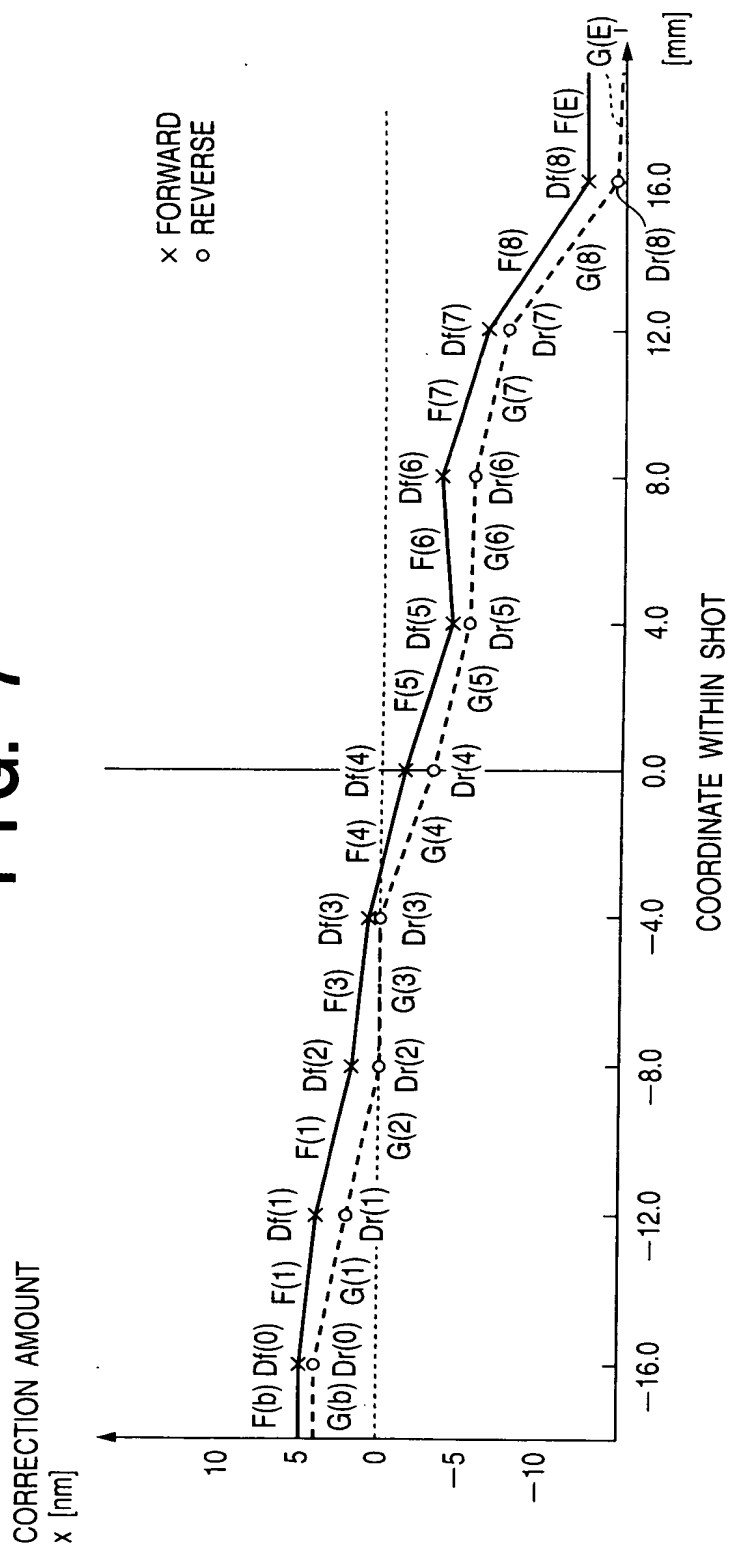


FIG. 8

DIRECTION OVERLAY CORRECTION

ORIGIN








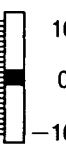









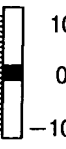
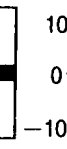

INTERVAL

MAX NUMBER OF DATA

CORRECTION TABLE

FORWARD :

AXIS X

									
DATA0	DATA1	DATA2	DATA3	DATA4	DATA5	DATA6	DATA7	DATA8	DATA9
									
DATA10	DATA11	DATA12	DATA13	DATA14	DATA15	DATA16	DATA17	DATA18	DATA19

AXIS X

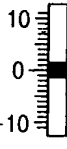






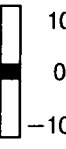


									
DATA0	DATA1	DATA2	DATA3	DATA4	DATA5	DATA6	DATA7	DATA8	DATA9



FIG. 9

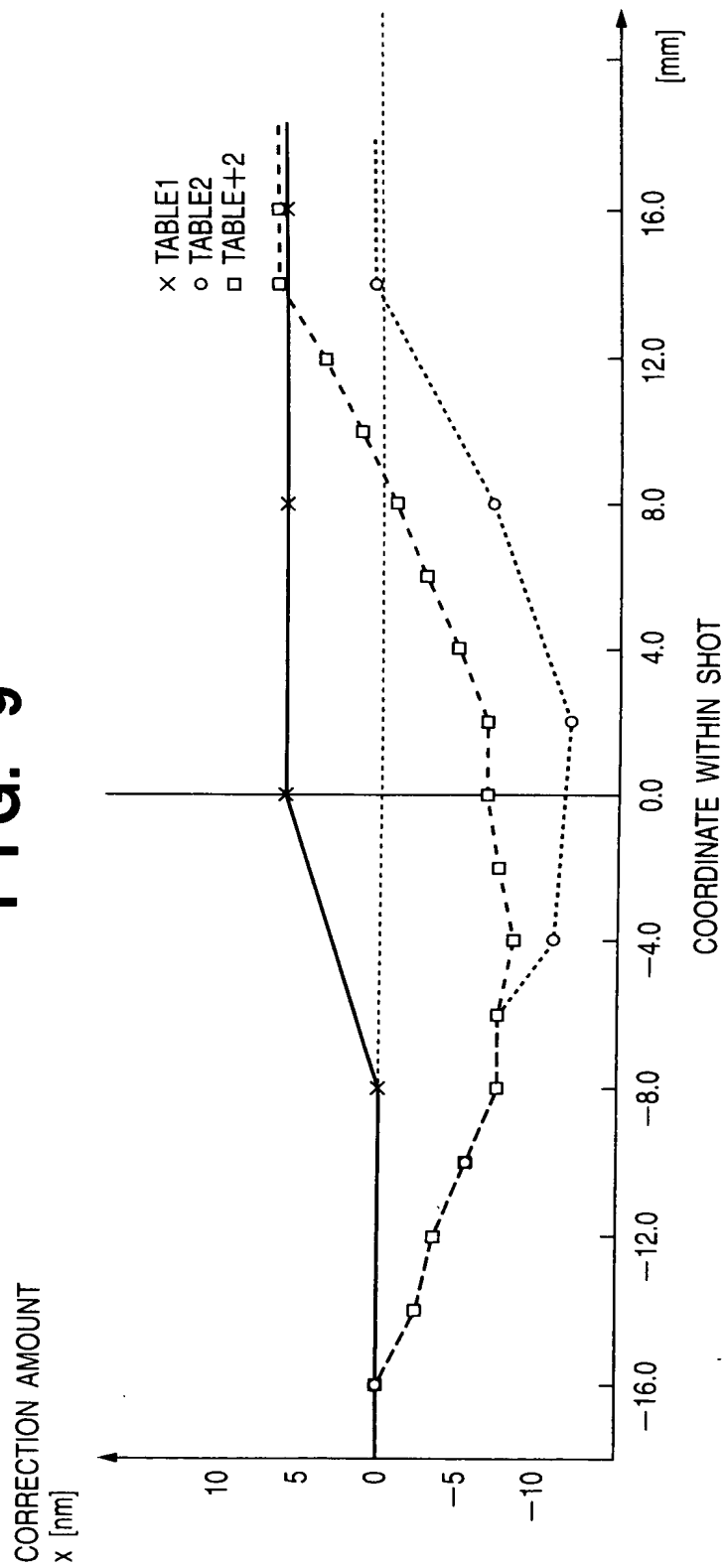


FIG. 10

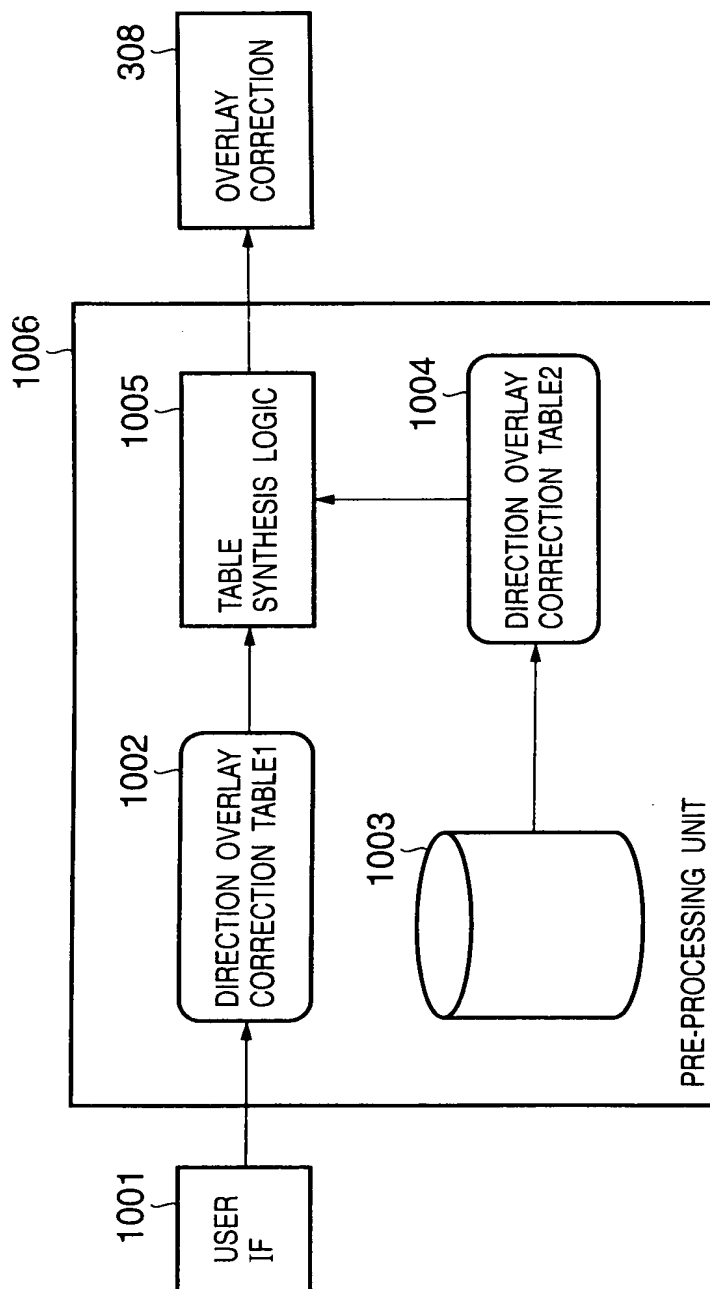
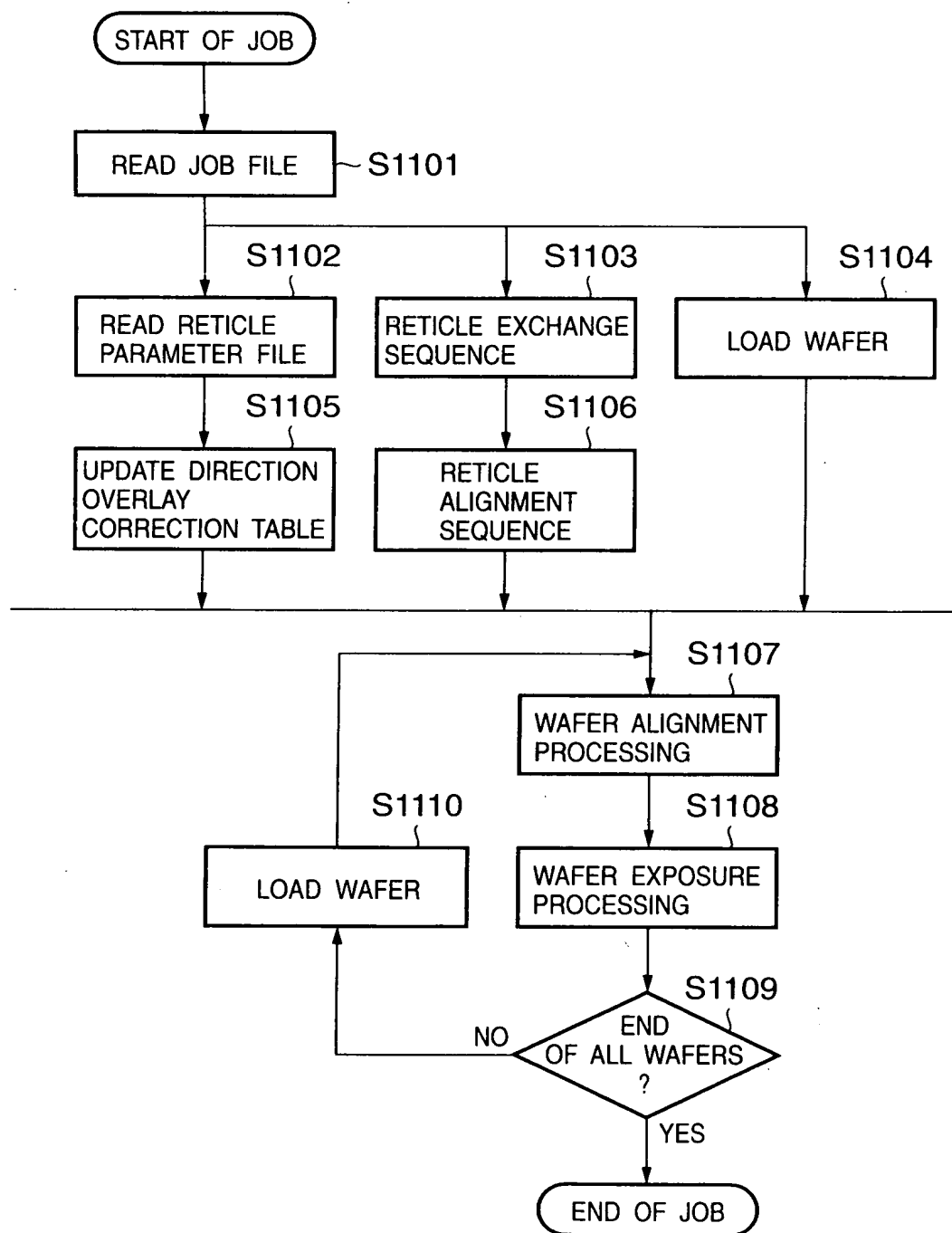
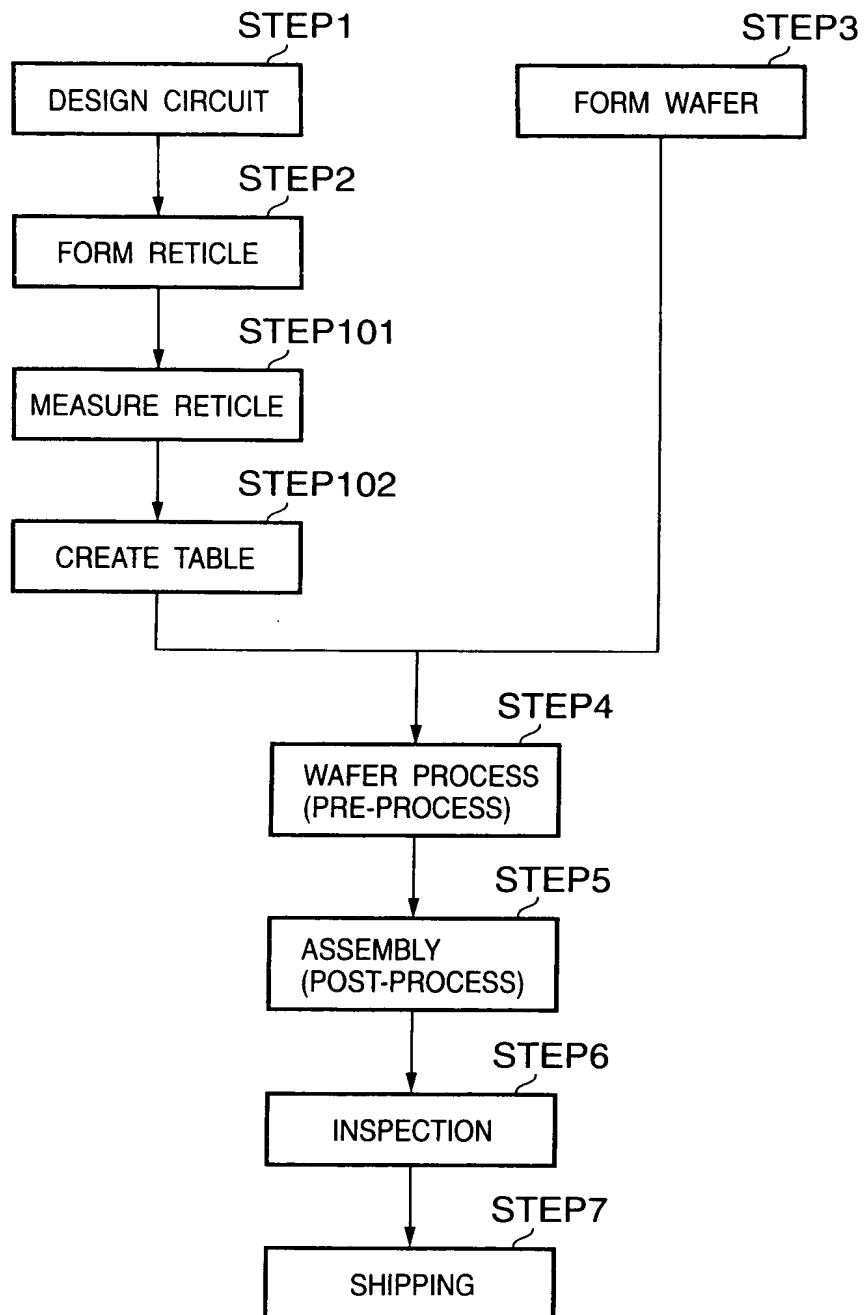


FIG. 11



**FIG. 12**

SEMICONDUCTOR DEVICE MANUFACTURING FLOW

FIG. 13

